

# From cyclotetrasilazane $[(CH_3)_2SiNH]_4$ via crystalline silicon nitride imide $Si_2N_2NH$ to $\alpha$ - $Si_3N_4$

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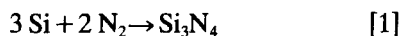
$\alpha$ - $Si_3N_4$  is synthesized by an ammonia thermal synthesis using a cyclic oligosilazane,  $[(CH_3)_2SiNH]_4$ , as the starting material.  $[(CH_3)_2SiNH]_4$  reacts in the presence of ammonia at 900 °C and 80 MPa pressure to give silicon nitride imide ( $Si_2N_2NH$ ). Subsequently,  $Si_2N_2NH$  is converted into  $\alpha$ - $Si_3N_4$  by thermal decomposition at 1500 °C and 0.1 MPa nitrogen with the simultaneous loss of  $NH_3$ .

**Keywords:** Silazane, synthesis, thermal, silicon nitride

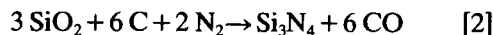
## INTRODUCTION

Due to their outstanding chemical and physical properties, pure silicon nitride ( $Si_3N_4$ ) ceramics and  $Si_3N_4/SiC$  ceramic composites have been considered as suitable materials for heat engine applications and are therefore of great economic interest. These materials possess high thermal stability and oxidation resistance, low electrical conductivity and low thermal expansion coefficients. They are also among the hardest materials which can be produced under atmospheric pressure.

Silicon nitride in its  $\alpha$  and  $\beta$  polymorphs was first characterized by X-ray diffraction in 1957.<sup>1</sup> The different industrial processing techniques involve high-temperature synthesis under atmospheric pressure starting from elemental silicon or silica as well as from low-molecular-weight silicon compounds,<sup>2-4</sup> according to the reaction equations [1]–[4].



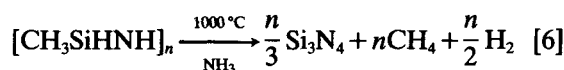
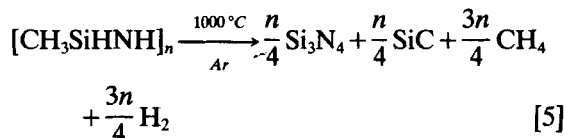
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These processes yield mixtures of  $\alpha$ - $Si_3N_4$  and  $\beta$ - $Si_3N_4$  in different ratios.<sup>2</sup> For the production of  $Si_3N_4$  materials with optimal properties, it is necessary to have a  $Si_3N_4$  starting powder with a high ratio of  $\alpha$ - $Si_3N_4$  ( $\alpha/(\alpha + \beta) > 95$  wt %), a low oxygen content ( $< 1.5$  wt %) and negligible contamination from carbon and metallic elements. The present work reports on the synthesis of  $\alpha$ - $Si_3N_4$  with a high  $\alpha/\beta$  ratio starting from easily accessible octamethylcyclotetrasilazane,  $[(CH_3)_2SiNH]_4$ .

## RESULTS

Oligo- and polysilazanes of the general formula  $[RSiR'NR'']_n$ , where R, R' and R'' represent H, CH<sub>3</sub> and C<sub>6</sub>H<sub>5</sub> respectively, have been intensively studied in recent years with regard to their application as precursors for  $Si_3N_4$ -based ceramics.<sup>5-12</sup> The synthesis proceeds by means of the thermal decomposition of silazane. Depending on the pyrolysis atmosphere, either  $Si_3N_4/SiC$  composites or pure  $Si_3N_4$  can be produced under atmospheric pressure.<sup>13-15</sup>

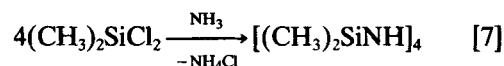


**Table 1** Elemental analysis of OMCTS-derived  $\text{Si}_2\text{N}_2\text{NH}$  produced by ammonia thermal synthesis and the resulting  $\alpha\text{-Si}_3\text{N}_4$  obtained by subsequent heat treatment of  $\text{Si}_2\text{N}_2\text{NH}$  at  $1500^\circ\text{C}$  in  $\text{N}_2$

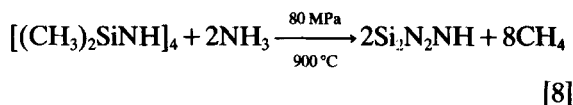
Reaction product	Composition (wt %)				
	Si	N	H	O	C
1000 $^\circ\text{C}$ : $\text{Si}_2\text{N}_2\text{NH}$	55.7	39.7	1.1	3.5	<0.2
(Calcd)	56.6	42.4	1.0	0	0
1500 $^\circ\text{C}$ : $\text{Si}_3\text{N}_4$	n.d. <sup>a</sup>	39.5	n.d.	1.2	n.d.
(Calcd)	60.0	40.0	0	0	0

<sup>a</sup> n.d., not determined.

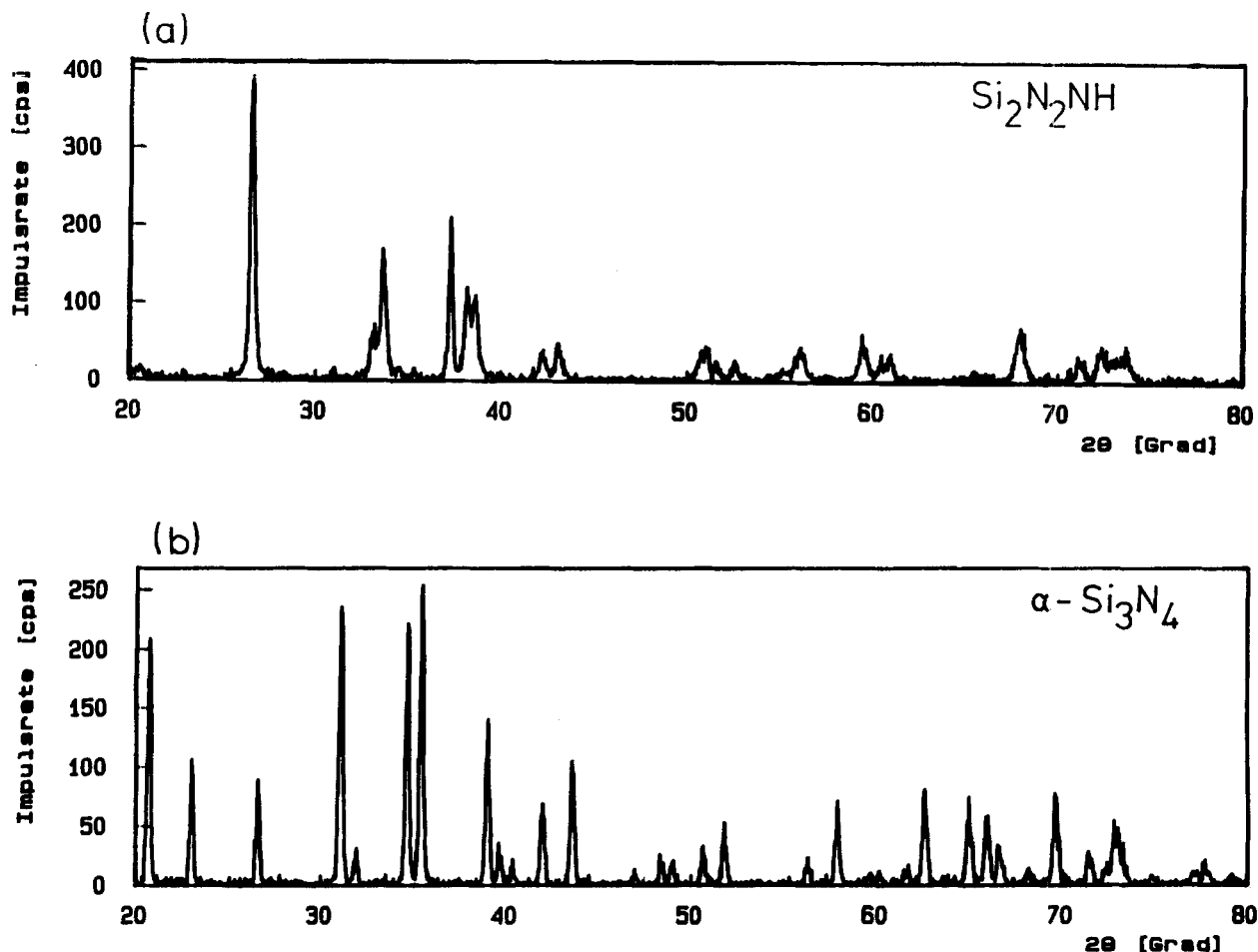
Generally, cyclic oligosilazanes are produced by the ammonolysis of chlorosilanes according to Eqn [7] representing the synthesis of octamethylcyclotetrasilazane (OMCTS):<sup>16</sup>



However, due to its low molecular weight, OMCTS cannot be directly pyrolysed by a solid-state reaction to silicon-based ceramics. We have now found that OMCTS reacts completely in an ammonia thermal synthesis under high pressure to crystalline silicon nitride imide ( $\text{Si}_2\text{N}_2\text{NH}$ ).



$\text{Si}_2\text{N}_2\text{NH}$  is considered to be an intermediate compound in the ammonolysis of  $\text{SiCl}_4$ , finally yielding  $\alpha\text{-Si}_3\text{N}_4$  at  $T > 1200^\circ\text{C}$ .<sup>3,6</sup> The X-ray diffraction pattern (Fig. 1a) of the reaction product is identical to that of  $\text{Si}_2\text{N}_2\text{NH}$  produced by the



**Figure 1** XRD patterns of (a) synthesized silicon nitride imide and (b)  $\text{Si}_2\text{N}_2\text{NH}$  heat-treated at  $1500^\circ\text{C}$  in  $\text{N}_2$ .

reaction of silicon with  $\text{KNH}_2$  in ammonia.<sup>17</sup> Optical transmission microscopy with crossed polarizers reveals that the material is completely crystallized.

Data from the elemental analysis of the solid material obtained are given in Table 1 and agree well with the calculated theoretical values for  $\text{Si}_2\text{N}_2\text{NH}$ . SEM investigation of crystalline  $\text{Si}_2\text{N}_2\text{NH}$  shows the existence of a microcrystalline powder with a spherical particle morphology and an average particle size of approximately  $0.15\ \mu\text{m}$  (Fig. 2).

At temperatures above  $1000^\circ\text{C}$ , the  $\text{Si}_2\text{N}_2\text{NH}$  reacts to produce  $\alpha\text{-Si}_3\text{N}_4$  with the simultaneous loss of  $\text{NH}_3$  according to the reaction:



In the X-ray diagram of the product heat-treated at  $1200^\circ\text{C}$ ,  $\alpha\text{-Si}_3\text{N}_4$  reflex peaks appear next to those of the  $\text{Si}_2\text{N}_2\text{NH}$ . After annealing at  $1500^\circ\text{C}$ , a 94 % yield of  $\alpha\text{-Si}_3\text{N}_4$  is obtained which can be determined from the X-ray results (Fig. 1b). The absence of X-ray diffraction lines corresponding to  $\beta\text{-Si}_3\text{N}_4$  indicates that the  $\beta/(\alpha + \beta)$  ratio is less than 2 wt %.<sup>18</sup> The data from the elemental analysis are included in Table 1.

SEM micrographs of the synthesized  $\alpha\text{-Si}_3\text{N}_4$  show the presence of rod-like crystallites with a particle size of less than  $0.7\ \mu\text{m}$  (Fig. 3).

A significant advantage of the synthesis of  $\text{Si}_3\text{N}_4$  from OMCTS is the application of relatively inex-

pensive and highly pure starting materials [ $(\text{CH}_3)_2\text{SiCl}_2$  and  $\text{NH}_3$ ]. The oligosilazane OMCTS can be obtained in a very pure form by distillation. In the subsequent ammonia thermal synthesis, gaseous methane ( $\text{CH}_4$ ) results exclusively as the by-product, which can be easily separated from the solid reaction product ( $\text{Si}_2\text{N}_2\text{NH}$ ). Therefore, as shown in this work,  $\text{Si}_2\text{N}_2\text{NH}$  is a suitable precursor for the production of  $\alpha\text{-Si}_3\text{N}_4$ , distinguished by its high phase purity and low oxygen contamination.

## EXPERIMENTAL

$[(\text{CH}_3)_2\text{SiNH}]_4$  (0.01 mol) was heat-treated in a pure  $\text{NH}_3$  atmosphere (approximately 80 MPa) for 72 h at  $900\text{--}1000^\circ\text{C}$  in an autoclave after humidity and oxygen had been evacuated. The material was subsequently cooled to room temperature and the reaction product separated from excess  $\text{NH}_3$  and any resulting  $\text{CH}_4$ . The crystalline  $\text{Si}_2\text{N}_2\text{NH}$  was heat-treated for 5 h at  $1200^\circ\text{C}$  and  $1500^\circ\text{C}$  in a nitrogen atmosphere. At  $1500^\circ\text{C}$ ,  $\alpha\text{-Si}_3\text{N}_4$  is obtained with a yield of 88.6 %, which corresponds to 94 % of the theoretical yield. Phase analysis was conducted by X-ray diffraction with  $\text{Cu K}\alpha$  radiation ( $\lambda = 150.64\ \text{pm}$ ) using a scintillation counting detector. X-ray detection was conducted in steps of  $0.03^\circ$  for 1 s. Photomicrographs of the powder morphology

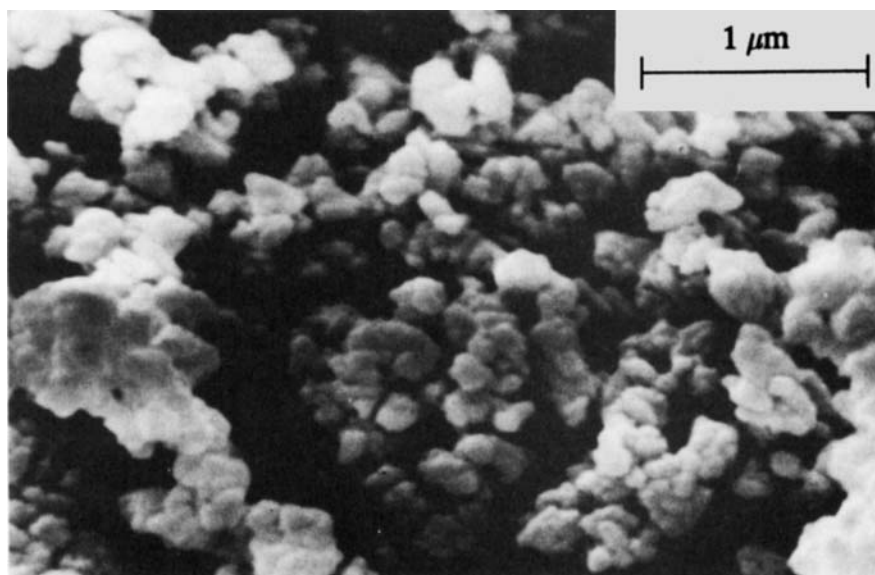


Figure 2 SEM micrograph of microcrystalline  $\text{Si}_2\text{N}_2\text{NH}$ .

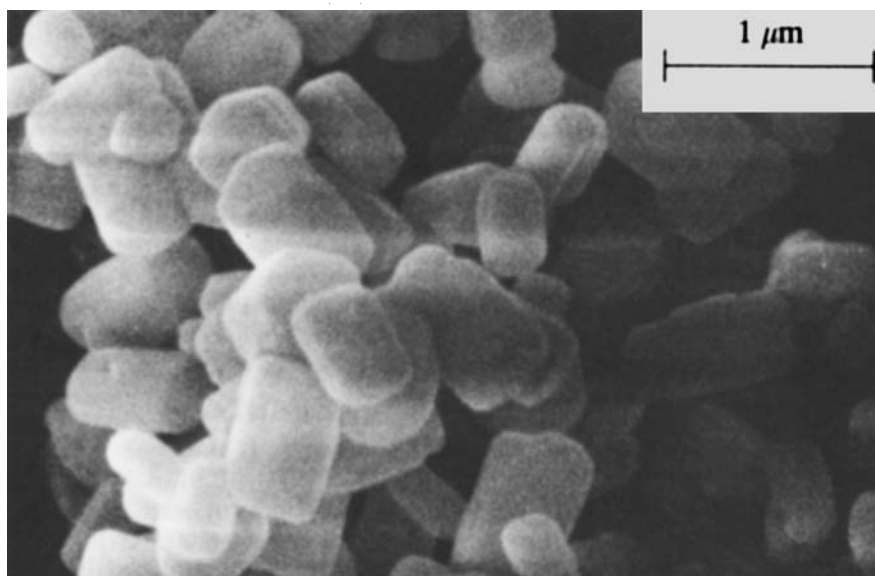


Figure 3 SEM micrograph of  $\alpha$ -Si<sub>3</sub>N<sub>4</sub> produced.

were taken on a Stereoscan 200 scanning electron microscope (Cambridge Instruments).

The C, N and O contents were determined by high-temperature combustion methods using C,S Analyser Model 244 and N,O Determinator Model TC 436 (LECO Corp., St. Joseph, MI, USA). Silicon was measured by means of optical emission spectrometry with inductively coupled plasma excitation.

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